





# Progress towards long lifetime high current polarized electron sources

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Brookhaven National Laboratory On behalf of the collaborations August 9, 2022





































GaAs-based photocathodes



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PHYSICAL REVIEW B

VOLUME 13, NUMBER 12

15 JUNE 1976

Photoemission of spin-polarized electrons from GaAs

Daniel T. Pierce\* and Felix Meier Laboratorium für Festkörperphysik, Eidgenössische Technische Hochschule, CH 8049, Zürich, Switzerland (Received 10 February 1976)





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#### Photo-Emission from GaAs





Superlattice GaAs ESP~92% (@780nm) QE~1.6% (@780nm)



GaAs-based photocathodes: Essential Attributes



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High Quantum Efficiency (QE)

Long charge lifetime

High Electron Spin Polarization (ESP)



#### GaAs-based photocathodes: Essential Attributes

High Quantum Efficiency (QE)

- Reducing Surface Contamination
- → Engineering the cathode, SL-DBR
- → Robust activation layer material

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Activation material that is robust against poor vacuum

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SL-GaAs, or SL-DBR



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High Electron Spin Polarization (ESP)

SL-GaAs, or SL-DBR



I will present our advances on each of these issues!

### Motivation:

Understanding surface roughness variations due to heat treatment

□ Understanding surface cleaning and its effect on QE

Evaluating chemical states of CsO/GaAs



#### Substrate Preparation and Characterization



Multiprobe system located in Center for Functional Nanomaterial (CFN) at Brookhaven National Laboratory (BNL).



### Substrate Preparation and Characterization







Schematic drawing of the multiprobe system at CFN, BNL



#### Substrate Preparation and Characterization - Surface Roughness



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STM - GaAs at different temperature, & after activation



#### Substrate Preparation and Characterization - Surface Roughness



STM - GaAs at different temperature, & after activation



J. Biswas et al. J. Appl. Phys. 128, 045308 (2020); https://doi.org/10.1063/5.0008969

#### Substrate Preparation and Characterization - Surface Roughness





#### RMS roughness at different stage of the activation

STM - GaAs at different temperature, & after activation



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Conclusion from Substrate Preparation and Characterization



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This preparation is optimal for the subsequent growth of thin activation material on it.

Reduced field emission and emittance growth.




















#### Pre-growth contamination analysis using XPS





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Conclusion from pre-growth contamination analysis



Conclusion from pre-growth contamination analysis

Although others have confirmed that presence of  $H_20$  leads to lower QE, we have shown presence of  $H_20$  causes other types of contamination to appear on the surface.



### Chemical analysis of CsO/GaAs cathode using AR-XPS/UPS

#### (a) 90° take-off angle



 $\alpha = electron \ take \ off \ angle$   $ID = Information \ depth$  $ID = d \ sin \alpha$ 



Chemical analysis of CsO/GaAs cathode using AR-XPS/UPS



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 $\Box$  We find the ratio of Cs & O on the activation layer, Cs:O  $\approx$  2:1

> No formation of previously proposed  $Cs_20$ , or  $Cs_{11}0_3$  compound in activation layer.



Conclusion from the chemical analysis of CsO/GaAs

□ This is a **first detailed chemical analysis** of Cs-O activation on GaAs.

❑ We find the ratio of Cs & O on the activation layer, Cs:O ≈ 2:1
➢ No formation of previously proposed Cs<sub>2</sub>O, or Cs<sub>11</sub>O<sub>3</sub> compound in activation layer.

□ XPS confirms that, surface start to lose Cs significantly at ~100°C, whereas **oxygen loss is significant even at 60°C**.

Laser illumination induced heating could destroy the cathode if temperature of the sample exceeds 60°C.



### New Activation Technique using Te, Cs, and O

We developed a new technique of activation employing a combination of cesium, tellurium, and oxygen that shows longer charge lifetime.





#### New Cs-Te and Cs-Te-O based Activation on GaAs



LEEM/XPEEM beamline located at NSLS II, BNL



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LEEM/XPEEM beamline located at NSLS II, BNL



Cathode chamber at CAD, BNL





#### New Cs-Te and Cs-Te-O based Activation on GaAs



Oxide desorption – LEED



#### New Cs-Te and Cs-Te-O based Activation on GaAs



(1x1), & defused (4x6) reconstruction

Oxide desorption – LEED



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(1x1), & defused (4x6) reconstruction

Oxide desorption – LEED













#### New Cs-Te and Cs-Te-O based Activation on GaAs



### Conclusion from the Cs-Te and Cs-Te-O based Activation

□ In Cs-Te activation QE at 532 nm: 6.6%

In Cs-Te-O activation QE at 532 nm: 8.8%; at 780 nm: 4.5%



Comparing Charge lifetime of Cs-Te-O based Activation



We demonstrated 5-6 times longer charge lifetime in a test chamber as compared to Cs-O/GaAs



#### Evaluating Surface Chemical States Cs-Te/GaAs



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#### Conclusion from Surface Chemical States Cs-Te/GaAs



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 $\Box$  Estimated Cs-Te layer thickness  $2 \pm 0.2 nm$ 


#### Evaluating Surface Chemical States Cs-Te-O/GaAs



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J. Biswas et al. AIP Advances 11, 025321 (2021); https://doi.org/10.1063/5.0026839

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 $\Box$  Estimated Cs-Te layer thickness  $1.6 \pm 0.2 nm$ 

























#### Evaluating the Negative Electron Affinity (NEA)



LEEM I/V of Cs-Te activated GaAs





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#### Cs-Te/GaAs

Final work function,  $\Phi_f = 1.4 \text{ eV}$ Effective NEA,  $\chi_{eff} = -0.02 \text{ eV}$ 



LEEM I/V of Cs-Te-O activated GaAs





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Cs-Te-O/GaAs

Final work function,  $\Phi_f = 1.0 \text{ eV}$ Effective NEA,  $\chi_{eff} = -0.42 \text{ eV}$ 







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□ On Cs-Te-O activation the achieved NEA;  $\chi_{eff} = -0.42 \text{ eV}$ This is comparable to CsO/GaAs NEA.

NEA is important because the thermalized electrons at the bottom of the conduction band can escape into the vacuum. Thus, QE increases the when larger NEA is achieved.



Superlattice (SL) GaAs



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Jin et el. Appl. Phys. Lett. 105, 203509 (2014)

#### Superlattice (SL) GaAs



SL – GaAs with Bragg Reflector



Jin et el. Appl. Phys. Lett. 105, 203509 (2014)

Quantum efficiency (%)

2.8

07

500

#### Superlattice (SL) GaAs



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Brookhaven National Laboratory Jin et el. Appl. Phys. Lett. 105, 203509 (2014)

#### Superlattice (SL) GaAs

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National Laboratory



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Motivation:



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Achieving both high QE and ESP at near bandgap energy is challenging.



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Achieving both high QE and ESP at near bandgap energy is challenging.

□ We need stable vendors.



We have been growing SL-DBR and characterizing them ➤ Details will follow in the Poster session: WEPA68



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GaAs	5 nm	p = 5x10 <sup>19</sup> cm <sup>-3</sup>	
GaAs <sub>0.62</sub> P <sub>0.38</sub>	4 nm	p = 5x10 <sup>17</sup> cm <sup>-3</sup>	
GaAs	4 nm	p = 5x10 <sup>17</sup> cm <sup>-3</sup>	
GaAs <sub>0.81</sub> P <sub>0.19</sub>	300 nm	p = 5x10 <sup>18</sup> cm <sup>-3</sup>	
AIAs <sub>0.78</sub> P <sub>0.22</sub>	65 nm	p = 5x10 <sup>18</sup> cm <sup>-3</sup>	<b>↓</b>
GaAs <sub>0.81</sub> P <sub>0.19</sub>	55 nm	p = 5x10 <sup>18</sup> cm <sup>-3</sup>	
GaAs <sub>0.81</sub> P <sub>0.19</sub>	2000 nm	p = 5x10 <sup>18</sup> cm <sup>-3</sup>	
GaAs->GaAs <sub>0.81</sub> P <sub>0.19</sub>	2750 nm	p = 5x10 <sup>18</sup> cm <sup>-3</sup>	
GaAs buffer	200 nm	p = 5x10 <sup>18</sup> cm <sup>-3</sup>	J
GaAs substrate		p > 1x10 <sup>18</sup> cm <sup>-3</sup>	



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Good agreement between the design reflectance and the measured one.

The sample photoemission efficiecny and the photoelectron spin polarization are currently being evaluated at BNL



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Achieved over 15% QE and ESP around 75% at near band gap photon energies.



J. Biswas et el. NAPAC 2022, Paper WEPA68



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- Cs-Te-O based GaAs shows NEA, and chemical states are identified for the first time.
  - Let's evaluate the robustness & charge lifetime of Cs-Te-O/GaAs in a gun



SL / SL-DBR with Cs-Te-O based activation



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- On SL-DBR we obtained QE exceeding 15% and ESP around 75% at near bandgap photon energy (i.e., ~780 nm)
  - Further tuning of SL layer, and growth method are ongoing, and activation with Cs-Te-O could lead to even higher QE.



# Thanks for your attentions!

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